



IFW

PATENT
8017-1104

IN THE U.S. PATENT AND TRADEMARK OFFICE

In re application of

Noriyuki SAKUMA et al.

Conf. 3651

Application No. 10/693,952

Group 1763

Filed October 28, 2003

Examiner Sylvia MacArthur

WAFER POLISHING METHOD AND WAFER POLISHING
APPARATUS IN SEMICONDUCTOR FABRICATION
EQUIPMENT

AMENDMENT

Assistant Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

December 7, 2004

Sir:

In response to the Office Action mailed September 8,
2004, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing
of claims which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.